

**Notice of References Cited**

Application/Control No.

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Applicant(s)/Patent Under  
Reexamination  
ELBOIM ET AL.

Examiner

JESSE DILLER

Art Unit

2187

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**U.S. PATENT DOCUMENTS**

*		Document Number	Date	Name	Classification
		Country Code-Number-Kind Code	MM-YYYY		
	A	US-			
	B	US-			
	C	US-			
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**FOREIGN PATENT DOCUMENTS**

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**NON-PATENT DOCUMENTS**

*	Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)				
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